

INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Attorney Docket Number	6333-67325
		Application Number	Not yet assigned
		Filing Date	Herewith
		First Named Inventor	Dickey
		Art Unit	Not yet assigned
		Examiner Name	Not yet assigned
U.S. PATENT DOCUMENTS			
Examiner's Initials*	Cite No. (optional)	Number	Date
✓		4,058,430	11/15/77
		4,389,973	6/28/83
		5,091,320	2/25/92
		5,257,132	10/26/93
		5,321,713	6/14/94
		5,438,952	8/8/95
		5,458,084	10/17/95
		5,677,594	10/14/97
		5,711,811	1/27/98
		5,712,528	1/27/98
		5,785,756	7/28/98
		5,804,919	9/8/98
		5,872,655	2/16/99
✓		6,449,403	9/10/02

EXAMINER SIGNATURE: <u>Ran</u>	DATE CONSIDERED: <u>5-25-07</u>
* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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FOREIGN PATENT DOCUMENTS			
Examiner's Initials*	Cite No. (optional)	Number	Date
		JP59045408	3/14/84 Japan
		JP6196809	7/15/94 Japan
		JP62002213	1/8/87 Japan
Examiner's Initials*	Cite No. (optional)	OTHER DOCUMENTS	
		T. Suntola, "Cost-effective Processing By Atomic Layer Epitaxy," <u>Thin Solid Films</u> , 225:96-98 (1993).	
		T. Suntola, "Atomic Layer Epitaxy," <u>Thin Solid Films</u> , 216:84-89 (1992).	

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT <small>JAN 26 2004</small> <small>RECEIVED PATENT & TRADEMARK OFFICE JAN 26 2004</small>		Attorney Docket Number	6333-67325
		Application Number	10/713,362
		Filing Date	November 14, 2003
		First Named Inventor	Dickey et al.
		Art Unit	
		Examiner Name	

U.S. PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Number	Date	Name
✓		4,915,476	4-10-90	Hall et al
		5,102,694	4-7-92	Taylor et al.
		5,164,040	11-17-92	Eres et al.
		5,458,084	10-17-95	Thorne et al.
		5,472,505	12-5-95	Lee et al
		5,724,144	3-3-98	Muller et al.
✓		5,916,365	6-29-99	Sherman

FOREIGN PATENT PUBLICATION

Examiner's Initials*	Cite No. (optional)	Number	Date	Country
✓		0 416 251 A2	3-13-91	European
✓		61018124	1-27-86	Japanese Abstract

OTHER DOCUMENTS

✓	Kukli et al., "Real-Time Monitoring in Atomic Layer Deposition of TiO ₂ from TiLi ₄ and H ₂ O—H ₂ O ₂ " Langmuir 2000, 16: 8122-8128
✓	Juppo et al., "In Situ Mass Spectrometry Study on Surface Reactions in Atomic Layer Deposition of Al ₂ O ₃ Thin Films from Trimethylalumin and Water", Langmuir 2000, 16, 4034-4039
✓	Aarik et al., "Anomalous effect of temperature on atomic layer deposition of titanium dioxide", Journal of Crystal Growth 220 (2000) 531-537

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